

Resource Summary Report

Generated by RRID on Aug 6, 2026

JEOL: EBG-300UA High Power Electron Beam Source

RRID:SCR_020160

Type: Tool

Proper Citation

JEOL: EBG-300UA High Power Electron Beam Source (RRID:SCR_020160)

Resource Information

URL: <https://www.jeolusa.com/PRODUCTS/Industrial-Equipment/High-Power-Electron-Beam-Sources>

Proper Citation: JEOL: EBG-300UA High Power Electron Beam Source (RRID:SCR_020160)

Description: High power electron beam source that is designed to uniformly deposit metal oxides onto wide plastic films or steel plates in continuous feed such as in magnetic tape manufacture for high density recording or in wrapping film manufacture with oxide barrier function

Resource Type: instrument resource

Keywords: Jeol, JEOL, High Power Electron Beam Source, Instrument Equipment, USEDit,

Availability: Commercially available

Resource Name: JEOL: EBG-300UA High Power Electron Beam Source

Resource ID: SCR_020160

Alternate IDs: Model_Number_EBG-300UA

Record Creation Time: 20220129T080349+0000

Record Last Update: 20260801T190644+0000

Ratings and Alerts

No rating or validation information has been found for JEOL: EBG-300UA High Power Electron Beam Source.

No alerts have been found for JEOL: EBG-300UA High Power Electron Beam Source.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.